

Notice of References Cited	Application/Control No. 10/805,871	Applicant(s)/Patent Under Reexamination KIM ET AL.	
	Examiner Natasha Young	Art Unit 1797	Page 1 of 1

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*	C	US-6,590,139 B1	07-2003	Lee et al.	800/24
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NON-PATENT DOCUMENTS

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	U	Machine translation of JP 11-347971 A. The Japanese Patent was provided in the IDS and has a date of 12/21/1999.
	V	Fung et al, A 2-D PVDF Force Sensing System for Micro-manipulation and Micro-assembly, May 2002, IEEE, 1489-1494.
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	X	DeVoe et al, Modeling and Optimal Design of Piezoelectric Cantilever Microactuators, Journal of Microelectromechanical Systems, Vol. 6, No. 3, September 1997, 266-270.

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.